

Syllabus for The International Summer School 2019

(Please fill in the form. Thank you very much.)			
課程名稱 Course name <small>at least in English, additionally in Chinese preferred</small>	(中) : 先進微機電系統科技 (Eng) : Advanced MEMS technology		
授課老師所屬單位 Offering dept. and university	Waseda University, Research organization for Nano & Life innovation		
開課時段 Session	() Session 1 (July 3 rd ~July 14 th) () Session 2 (July 17 th ~ July 28 th) (✓) Session 3 (July 29 th ~August 2 nd) () Session 4 (August 14 st ~August 25 th)		<input checked="" type="checkbox"/> 5 days /3 hours a day (6 hr for August 2 nd) <input type="checkbox"/> 3 days /6 hours a day
開課日期 *Teaching Dates (18hours)	Dates : from July 29 to Aug. 2 2019		<input checked="" type="checkbox"/> Morning (9:00~12:00) <input type="checkbox"/> Afternoon (14:00~17:00)
課程開辦系所 Hosting Department	Graduate institute of precision engineering		
授課教師資料 Offering teacher's information	Name: Jun MIZUNO Tel. / mobile phone number: +81-80-2066-7960 Email: mizuno@waseda.jp Website: http://www.waseda.jp/sem-shoji-GIT/profile.html		
學經歷 Curriculum vitae	Education: Device science, PhD. Professional appointment: Professor in Research Institute of Nano-technology, Research Organization for Nano & Life Innovation, 513 Tsurumaki-cho, Waseda, Shinjuku-ku, Tokyo 162-0041, Japan Other qualification: Visiting Professor in Kyushu University		
學分數 Credit(s)	1	授課對象 Target audience	Postgraduate
課程目標 Goal of this course <small>description within 150 words</small>	To understand the content of each technology of MEMS. To understand the characteristics of the device fabricated by MEMS technology.		
課程簡述 Course description <small>description within 350 words</small>	To understand the following technologies of MEMS: (A) Classroom learning ① Cleaning ② Photo-lithography ③ Film formation / deposition ④ Etching ⑤ Bonding / Packaging ⑥ Measurement and evaluation / characterization ⑦ Examples of device application (B) Practical learning (Experiment) Fabricate the fine structures using nanoimprint and evaluate / characterize them		

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課程內容 / 授課大綱 Course content / outline	Classroom learning 1 st day; Cleaning, Photo-lithography 2 nd day; Film formation / deposition, Etching 3 rd day; Bonding / packaging, Measurement and evaluation / characterization 4 th day; Examples of device application Practical learning 5 th day; (morning) Fabricate the fine structures using nanoimprint (afternoon) Fabricate, evaluate and characterize the students
學習評量方式 Assessment / grading policy	(1) Report: 50% (2) Examination: 50%
課程目標之教學方法 Teaching methods for this course	Power point presentation and blackboard.
教科書&參考書目 Textbook & other reference	Electronics data prepare by Prof. Mizuno